

Receipt  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Watson et al.

Attorney Docket No.:  
NIKOP002/PA0 327

Application No.: 09/870,881

Examiner: Unassigned

Filed: May 30, 2001

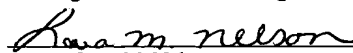
Group: Unassigned

Title: CANTILEVER RETICLE STAGE FOR  
ELECTRON BEAM PROJECTION  
LITHOGRAPHY SYSTEM

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Washington, DC 20231 on August 8, 2001.

Signed:

  
Lara M. Nelson

**REQUEST FOR CORRECTED FILING RECEIPT**

Commissioner for Patents  
**Office of Initial Patent Examination**  
**Customer Service Center**  
Washington, DC 20231

Sir:

Enclosed is a copy of the Filing Receipt for the above-identified patent application. Please reprint the Filing Receipt as follows and mail the corrected copy to the undersigned.

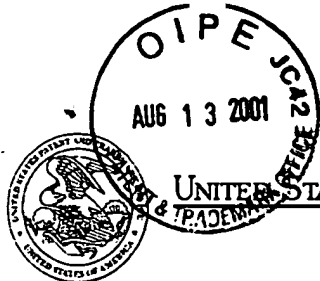
Change the Title "CANTILEVER RETICLE STAGE FOR ELECTRON BEAM PROJECTION LITHOGRAPHY SYSTME" to --CANTILEVER RETICLE STAGE FOR ELECTRON BEAM PROJECTION LITHOGRAPHY SYSTEM--.

Applicant believes that no fees are due in connection with the filing of this request. If any fees are due, the Commissioner is authorized to charge such fees to our Deposit Account No. 500388 (Order No. NIKOP002).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP

  
Steve D Beyer  
Registration No. 31,234

P.O. Box 778  
Berkeley, CA 94704-0778



## UNITED STATES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS  
UNITED STATES PATENT AND TRADEMARK OFFICE  
WASHINGTON, D.C. 20231  
www.uspto.gov

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/870,881	05/30/2001	2812	916	NIKOP002	15	27	4

CONFIRMATION NO. 8984

022434  
BEYER WEAVER & THOMAS LLP  
P.O. BOX 778  
BERKELEY, CA 94704-0778

## FILING RECEIPT



\*OC00000006354178\*

Date Mailed: 07/27/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. **If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).**

## Applicant(s)

Douglas C. Watson, Campbell, CA;  
Michael Kovalerchik, Castro Valley, CA;  
W. Thomas Novak, Hillsborough, CA;

## Domestic Priority data as claimed by applicant

THIS APPLN CLAIMS BENEFIT OF 60/226,409 08/18/2000

## Foreign Applications

If Required, Foreign Filing License Granted 07/27/2001

Projected Publication Date: To Be Determined - pending completion of Corrected Papers

Non-Publication Request: No

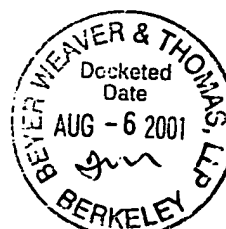
Early Publication Request: No

## Title

Cantilever reticle stage for electron beam projection lithography system SYSTEM

## Preliminary Class

438



SDB / SDB3